

<b>Notice of References Cited</b>	Application/Control No. 10/674,467	Applicant(s)/Patent Under Reexamination ONISHI ET AL.	
	Examiner Anthony Quash	Art Unit 2881	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6,440,619	08-2002	Feldman, Martin	430/30
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

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	N					
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	PC T: WO 01/11431 A2, inventor: Moffatt, Stephen, □□Method and Apparatus of Holding Semiconductor Wafers for Lithography and Other Wafer Processes, 15 February 2001 (15.02.2001), abstract, figure 1, pages 1,4,5,7,9-10,15-17.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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